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Adhesive transfer at copper/diamond interface and adhesion reduction mechanism with fluorine passivation: A first-principles study

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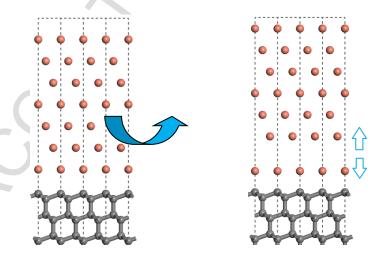
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Graphical Abstract

- **1.**The interfacial structure change, electronic and mechanical properties of Cu/diamond and interface with fully F passivation (Cu/diamond:F) have been evaluated through first-principles calculations.
- **2.**The study shows that Cu(111)/diamond(111) interface exhibits the special phenomenon of adhesive transfer due to adhesion, and this contribute to different frictional properties among soft metal.
- **3.**Passivation of fluorine on diamond surface reduces work of separation of the Cu/diamond interface significantly, from 3.64J/m² to 0.02J/m².
- **4.**We also gain that fluorine might be a kind of promising adhesion-reducing element at interface and improve related tribological characteristics of Cu(111)/diamond(111) system.
- **5.**The results of this study benefit the understanding of different tribological properties of Cu/DLC system, adhesion reduction mechanism of fluorine at interface and its effect on tribological behavior at atomic scale.



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